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(54) **OPTICAL SENSING SYSTEM AND A METHOD OF DETERMINING A CHANGE IN AN EFFECTIVE REFRACTIVE INDEX OF A RESONATOR OF AN OPTICAL SENSING SYSTEM**

(75) Inventors: **Junfeng Song**, Singapore (SG); **Xianshu Luo**, Singapore (SG); **Qing Fang**, Singapore (SG); **Mingbin Yu**, Singapore (SG); **Guo Qiang Patrick Lo**, Singapore (SG)

(73) Assignee: **Agency for Science, Technology and Research**, Singapore (SG)

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Dec. 28, 2010 (SG) 201009654-3

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H01S 3/10	(2006.01)
G01N 21/77	(2006.01)
G02B 6/293	(2006.01)
H01S 5/14	(2006.01)
H01S 5/026	(2006.01)
G01N 21/45	(2006.01)

(52) **U.S. Cl.**

CPC ***G01N 21/7746*** (2013.01); *H01S 5/141* (2013.01); *H01S 5/026* (2013.01); ***G01N 21/41*** (2013.01); *G01N 2021/458* (2013.01); ***G02B 6/29341*** (2013.01)

(58) **Field of Classification Search**

USPC 356/128; 385/129, 131, 146, 27; 250/227.4, 492.3; 372/20

See application file for complete search history.

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Primary Examiner — Sang Nguyen

(74) *Attorney, Agent, or Firm* — K. David Crockett, Esq.; Niky Economy Syrengelas, Esq.; Crockett & Crockett, PC

(57) **ABSTRACT**

According to embodiments of the present invention, an optical sensing system is provided. The optical sensing system includes a resonator arrangement including a first resonator, wherein an effective refractive index of the first resonator is changeable in response to a change in a refractive index of a cladding of the first resonator, and a second resonator to which a current or voltage being adjustable in response to a change in the effective refractive index of the first resonator is applied, wherein the optical sensing system is configured to determine the change in the effective refractive index of the first resonator based on a change in the current or voltage applied to the second resonator. Further embodiments provide a method of determining a change in an effective refractive index of a resonator of an optical sensing system.

21 Claims, 10 Drawing Sheets

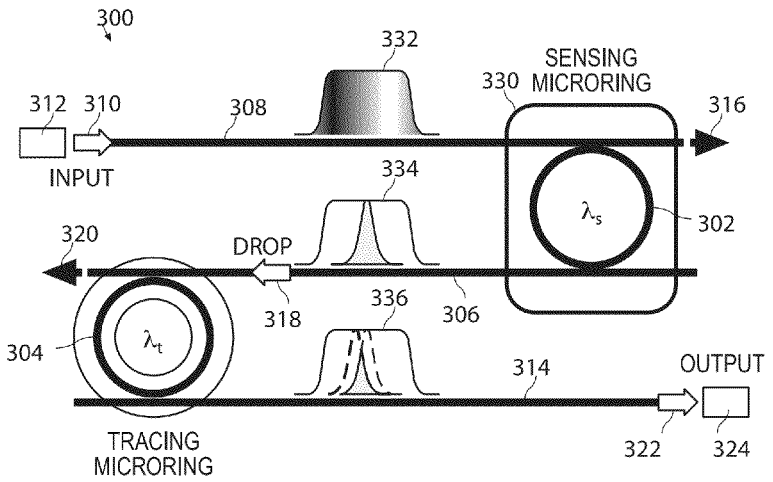

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FIG. 1A

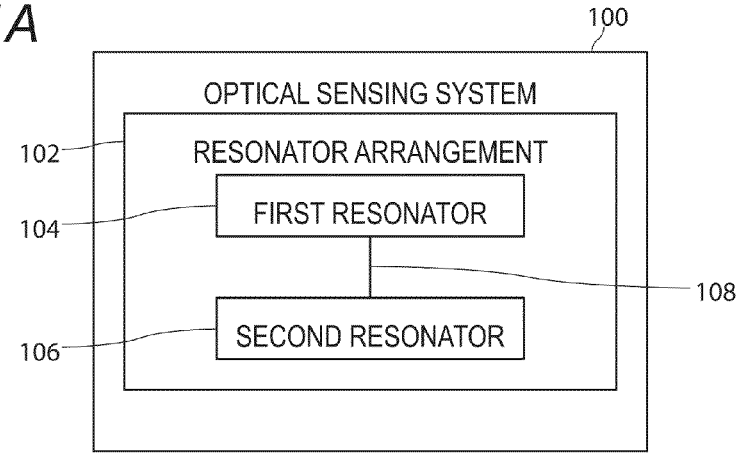
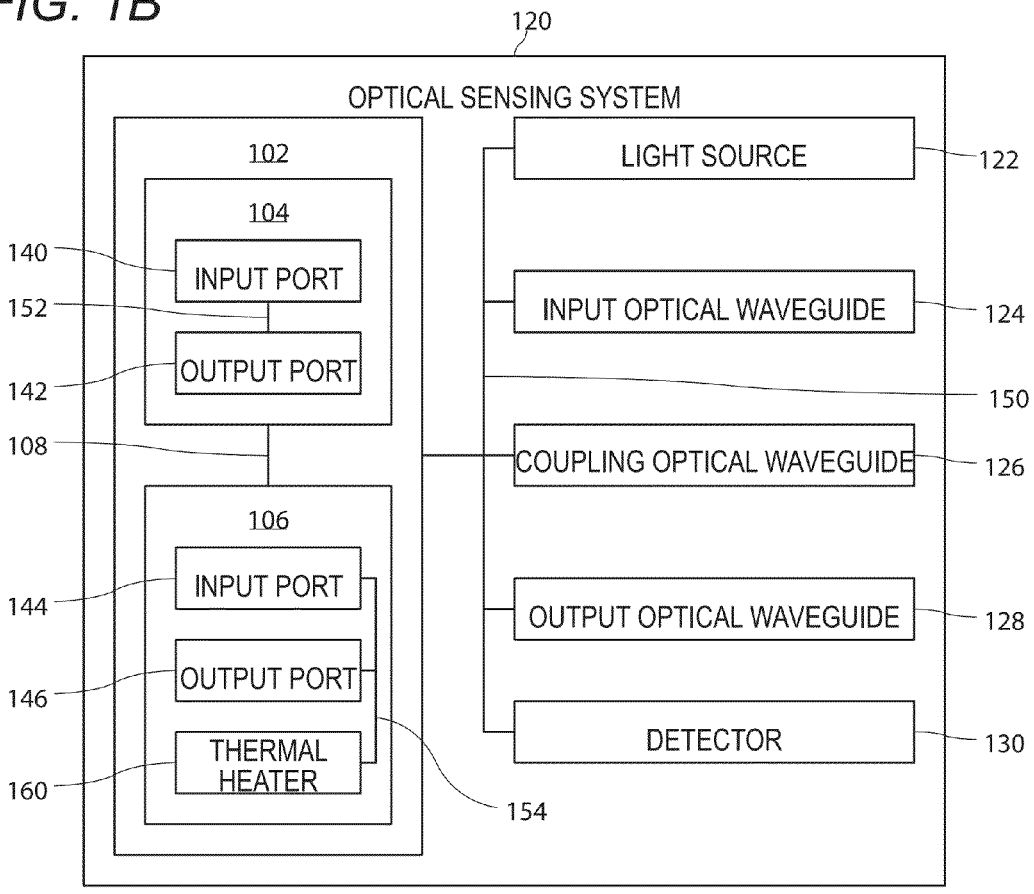

100
OPTICAL SENSING SYSTEM
102
RESONATOR ARRANGEMENT
104
FIRST RESONATOR
108
106
SECOND RESONATOR

FIG. 1B


120
OPTICAL SENSING SYSTEM
102
104
140
INPUT PORT
152
OUTPUT PORT
142
108
106
144
INPUT PORT
146
OUTPUT PORT
160
THERMAL HEATER
154
LIGHT SOURCE
122
INPUT OPTICAL WAVEGUIDE
124
150
COUPLING OPTICAL WAVEGUIDE
126
OUTPUT OPTICAL WAVEGUIDE
128
DETECTOR
130

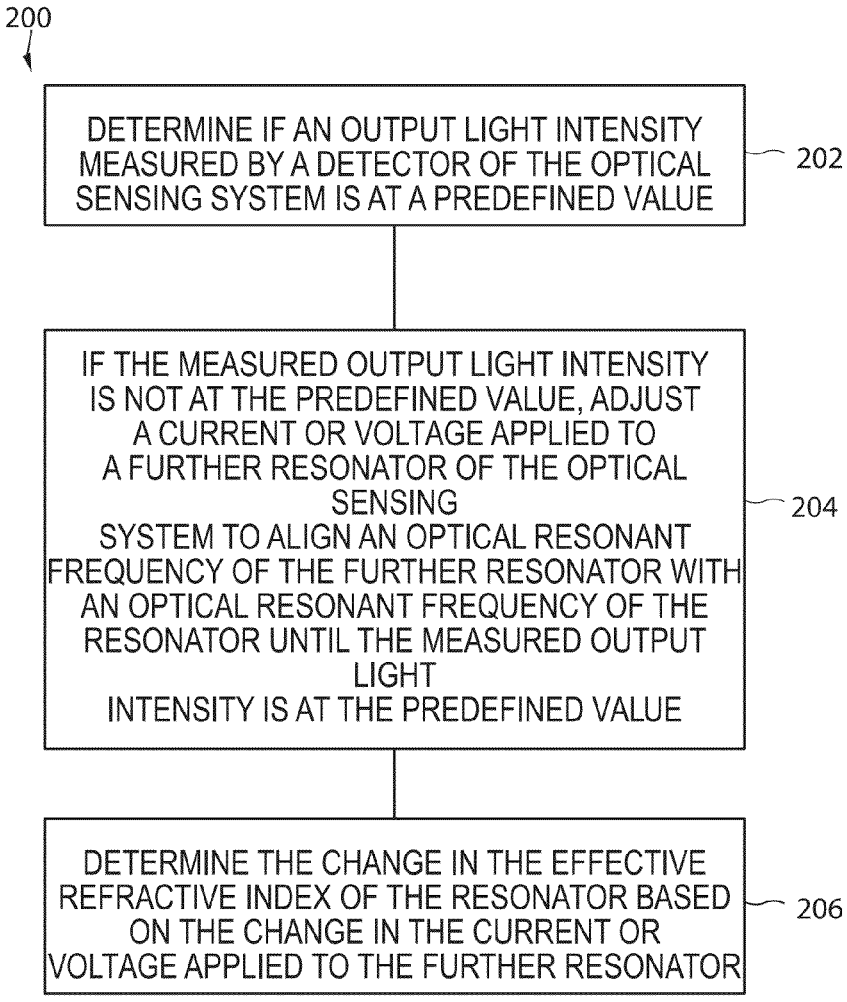

200
DETERMINE IF AN OUTPUT LIGHT INTENSITY MEASURED BY A DETECTOR OF THE OPTICAL SENSING SYSTEM IS AT A PREDEFINED VALUE
202
IF THE MEASURED OUTPUT LIGHT INTENSITY IS NOT AT THE PREDEFINED VALUE, ADJUST A CURRENT OR VOLTAGE APPLIED TO A FURTHER RESONATOR OF THE OPTICAL SENSING SYSTEM TO ALIGN AN OPTICAL RESONANT FREQUENCY OF THE FURTHER RESONATOR WITH AN OPTICAL RESONANT FREQUENCY OF THE RESONATOR UNTIL THE MEASURED OUTPUT LIGHT INTENSITY IS AT THE PREDEFINED VALUE
204
DETERMINE THE CHANGE IN THE EFFECTIVE REFRACTIVE INDEX OF THE RESONATOR BASED ON THE CHANGE IN THE CURRENT OR VOLTAGE APPLIED TO THE FURTHER RESONATOR
206

FIG. 2

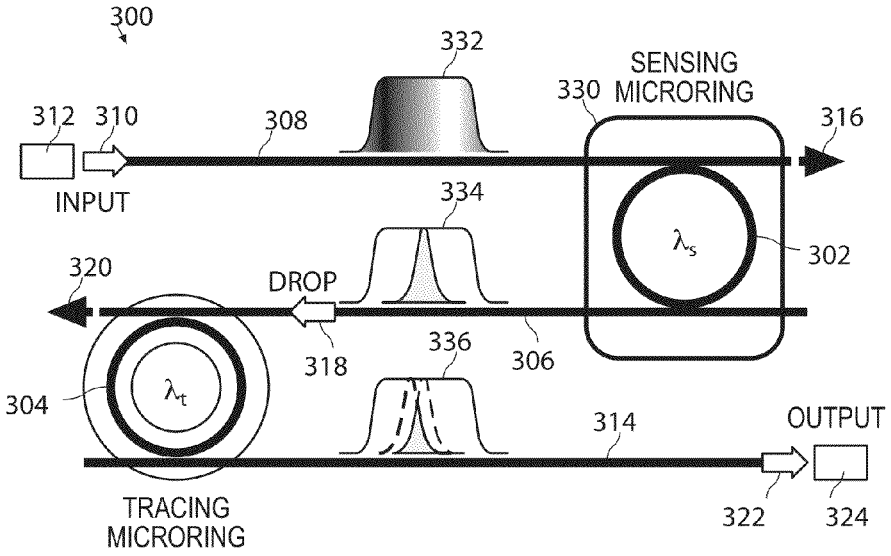

300
332
SENSING
330 MICRORING
312 310
308
316
INPUT
334
λ_s
302
320
DROP
318
336
306
304
λ_t
314
OUTPUT
TRACING
MICRORING
322
324

FIG. 3A

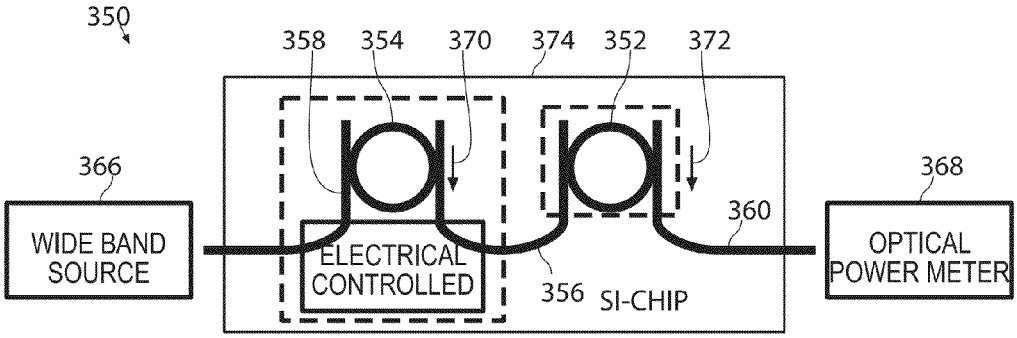

350
358
354
370
374
352
372
366
368
360
WIDE BAND
SOURCE
ELECTRICAL
CONTROLLED
356
SI-CHIP
OPTICAL
POWER METER

FIG. 3B

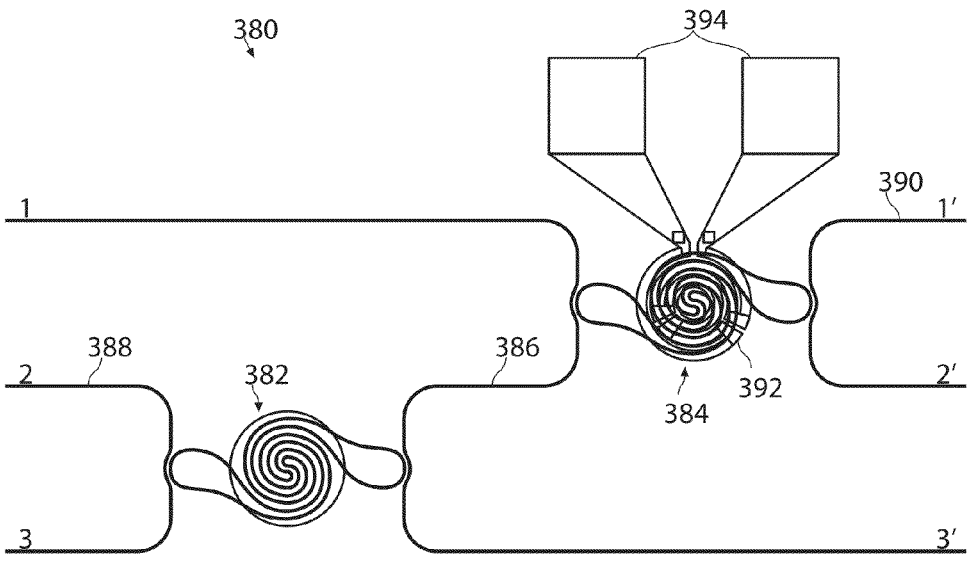


FIG. 3C

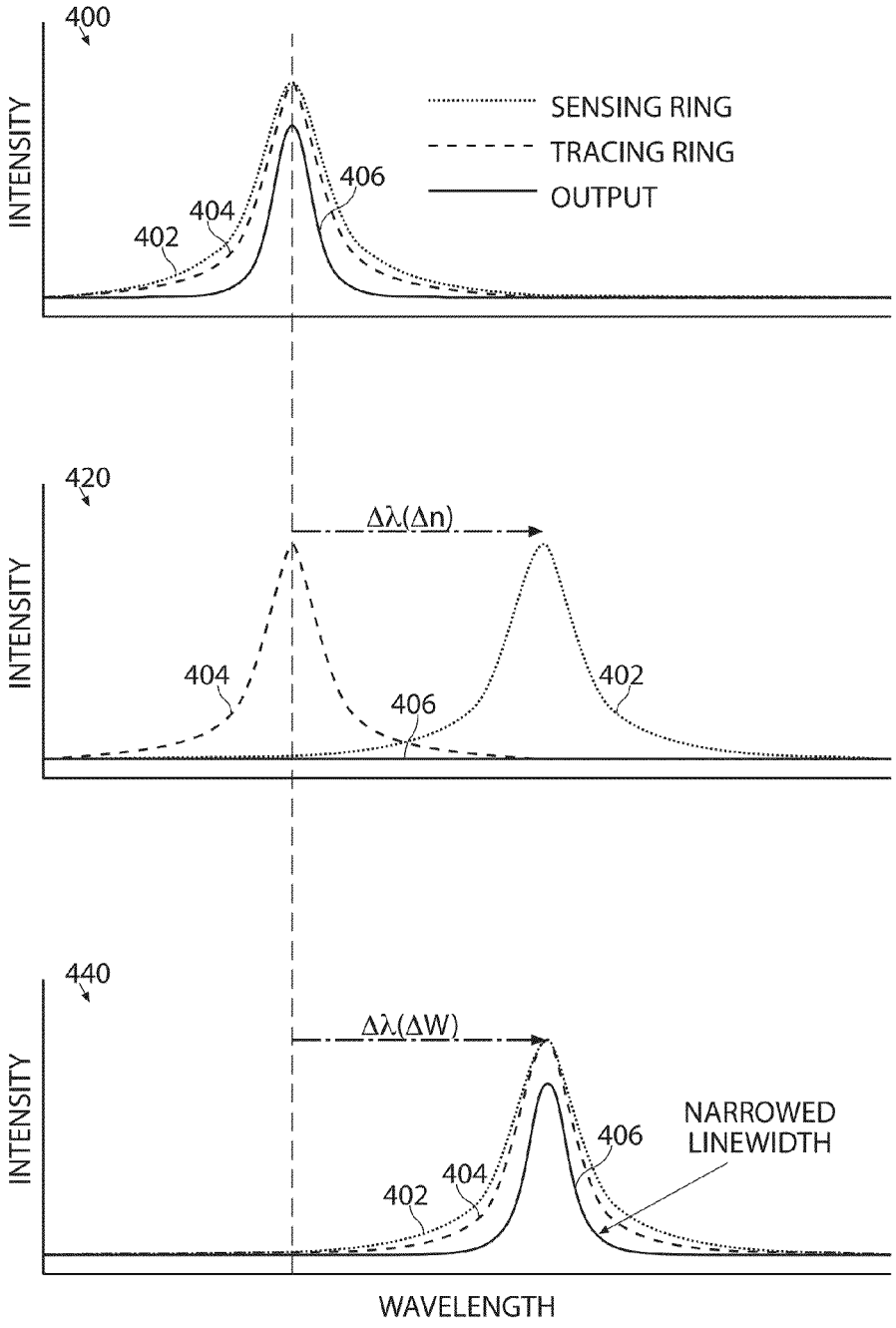

400
INTENSITY
SENSING RING
TRACING RING
OUTPUT
402
404
406
420
INTENSITY
Δλ(Δn)
404
406
402
440
INTENSITY
Δλ(ΔW)
NARROWED
LINEWIDTH
406
404
402
WAVELENGTH

FIG. 4

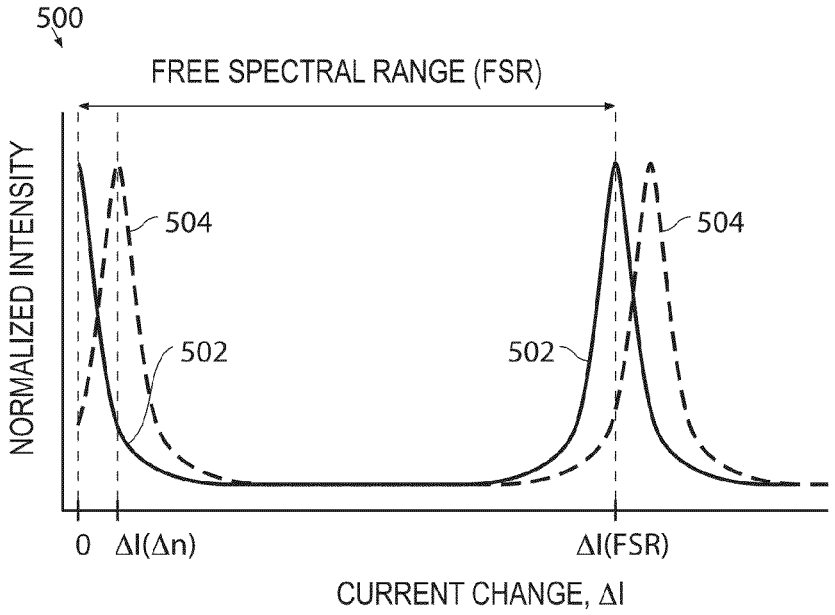

500
FREE SPECTRAL RANGE (FSR)
NORMALIZED INTENSITY
504
502
502
504
0
ΔI(Δn)
ΔI(FSR)
CURRENT CHANGE, ΔI

FIG. 5

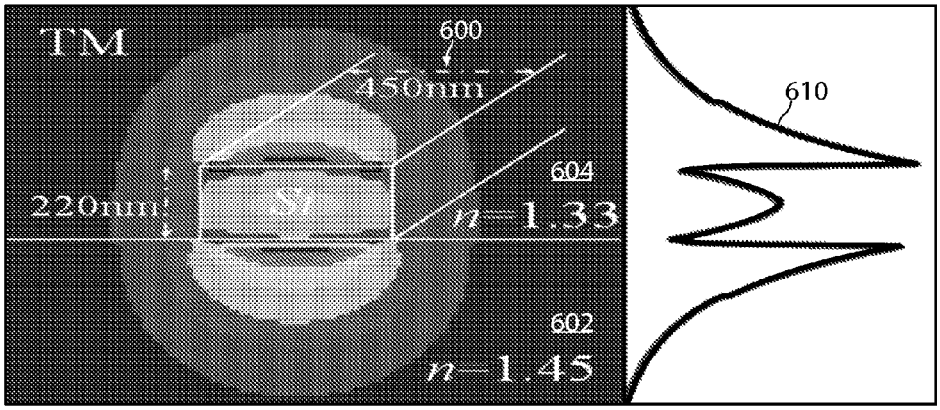

TM
600
450nm
610
604
220nm
n=1.33
602
n=1.45

FIG. 6A

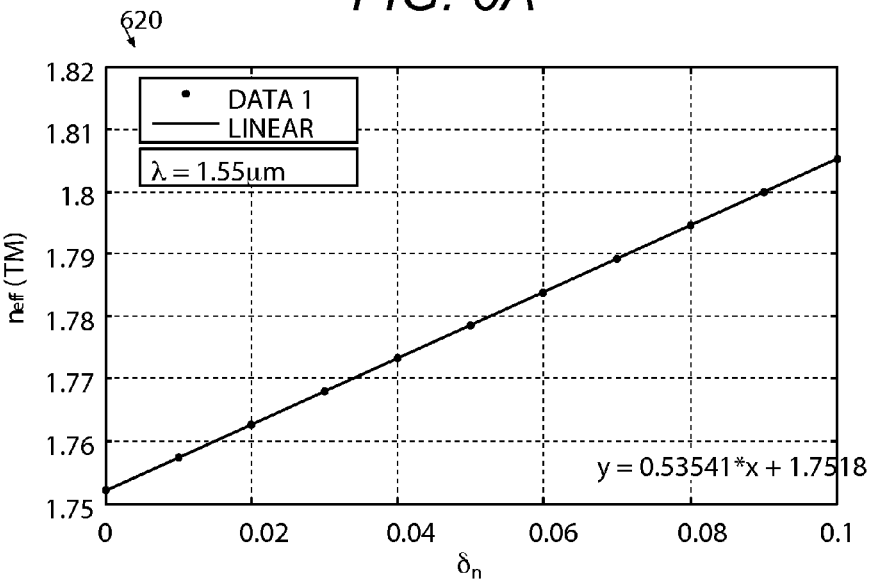

620
DATA 1
LINEAR
λ = 1.55μm
y = 0.53541*x + 1.7518
neff (TM)
δn
1.82
1.81
1.8
1.79
1.78
1.77
1.76
1.75
0
0.02
0.04
0.06
0.08
0.1

FIG. 6B

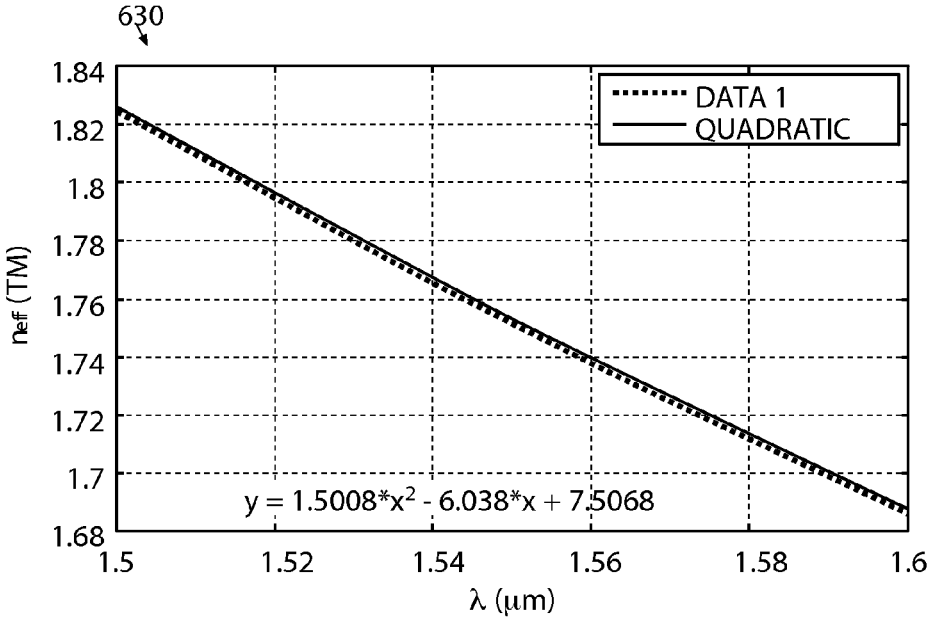

630
1.84
1.82
1.8
1.78
1.76
1.74
1.72
1.7
1.68
neff (TM)
1.5
1.52
1.54
1.56
1.58
1.6
λ (μm)
DATA 1
QUADRATIC
y = 1.5008*x2 - 6.038*x + 7.5068

FIG. 6C

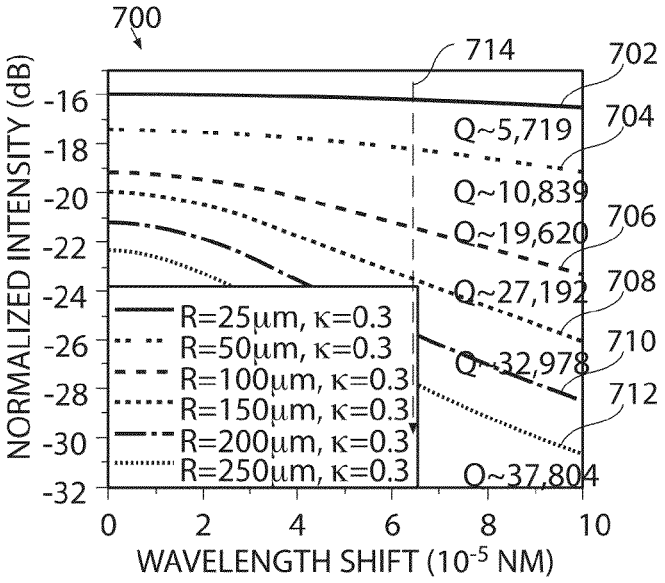

700
714
702
704
706
708
710
712
Q~5,719
Q~10,839
Q~19,620
Q~27,192
Q~32,978
Q~37,804
R=25μm, κ=0.3
R=50μm, κ=0.3
R=100μm, κ=0.3
R=150μm, κ=0.3
R=200μm, κ=0.3
R=250μm, κ=0.3
NORMALIZED INTENSITY (dB)
-16
-18
-20
-22
-24
-26
-28
-30
-32
0
2
4
6
8
10
WAVELENGTH SHIFT (10-5 NM)

FIG. 7A

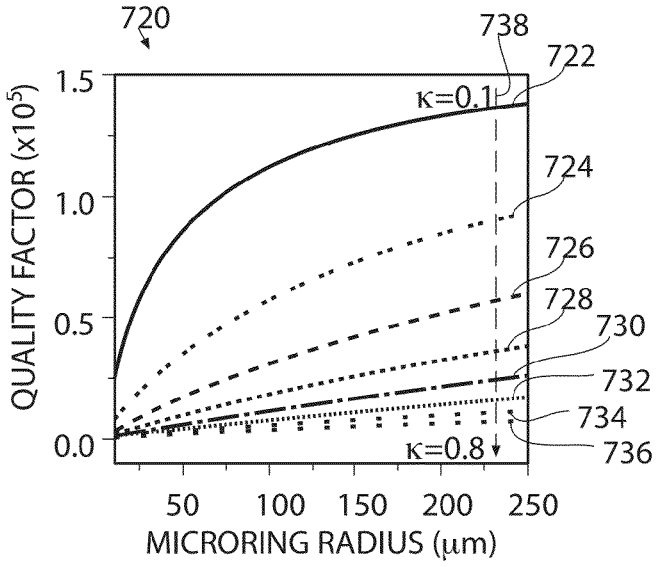

720
738
722
724
726
728
730
732
734
736
κ=0.1
κ=0.8
QUALITY FACTOR (x10^5)
1.5
1.0
0.5
0.0
50
100
150
200
250
MICRORING RADIUS (μm)

FIG. 7B

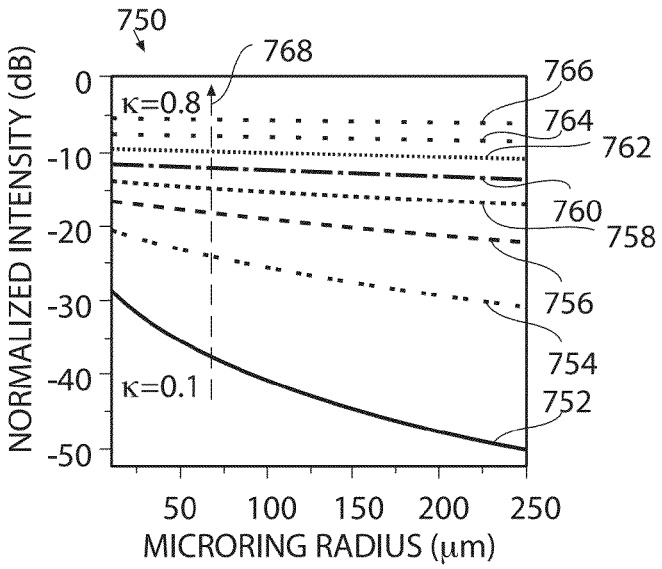

750
768
766
764
762
760
758
756
754
752
κ=0.8
κ=0.1
0
-10
-20
-30
-40
-50
NORMALIZED INTENSITY (dB)
50
100
150
200
250
MICRORING RADIUS (μm)

FIG. 7C

OPTICAL SENSING SYSTEM AND A METHOD OF DETERMINING A CHANGE IN AN EFFECTIVE REFRACTIVE INDEX OF A RESONATOR OF AN OPTICAL SENSING SYSTEM

CROSS-REFERENCE TO RELATED APPLICATION

This application claims the benefit of priority of Singapore patent application No. 201009654-3, filed 28 Dec. 2010, the content of it being hereby incorporated by reference in its entirety for all purposes.

TECHNICAL FIELD

Various embodiments relate to an optical sensing system and a method of determining a change in an effective refractive index of a resonator of an optical sensing system.

BACKGROUND

Label-free optical biological/chemical sensors are essential in the application of medical diagnosis, healthcare and environmental monitoring, amongst others. Among all the approaches, silicon optical microresonator-based biosensors are regarded to be very promising due to their high sensitivity to refractive index change (~10^{-4}-10^{-7} RIU (refractive index unit)), comparable to the conventional surface plasmon resonance (SPR) technique sensitivity), compact footprint (~10's μm-~100 μm), and potential large-scale-integration with microfluidics.

Single microring resonator-based biosensors in silicon-on-insulator (SOI) have been demonstrated using either conventional microrings [K. De Vos, et al., *Opt. Express* 15, pp. 7610-7615 (2008); D. Xu, et al., *Opt. Express* 16, pp 15137-15148 (2008); M. Iqbal, et al., *IEEE J. Select. Top. Quantum Electron.* 16, pp. 654-661 (2010).] or slot-waveguide microring [T. Claes, et al., *J. Photon.* 1, pp. 197-204 (2008).]. The demonstrated detection limit ranges from 10^{-5}-10^{-7} RIU.

However, for nearly all the demonstrated microresonator sensors, the wavelength-scanning method using wavelength-tunable lasers was considered to be the "default" technique for measuring sharp resonance wavelength shift. The wavelength-scanning method requires high-resolution wavelength tunable lasers in order to measure the sharp resonance wavelength shift, in which the detection limit is limited by the laser resolution. Furthermore, high-resolution wavelength-scanning lasers are very expensive and not suitable for point-of-care applications.

SUMMARY

According to an embodiment, an optical sensing system is provided. The optical sensing system may include a resonator arrangement including a first resonator, wherein an effective refractive index of the first resonator is changeable in response to a change in a refractive index of a cladding of the first resonator, and a second resonator to which a current or voltage being adjustable in response to a change in the effective refractive index of the first resonator is applied, wherein the optical sensing system is configured to determine the change in the effective refractive index of the first resonator based on a change in the current or voltage applied to the second resonator.

According to an embodiment, a method of determining a change in an effective refractive index of a resonator of an optical sensing system is provided. The method may include determining if an output light intensity measured by a detector of the optical sensing system is at a predefined value, if the measured output light intensity is not at the predefined value, adjusting a current or voltage applied to a further resonator of the optical sensing system to align an optical resonant frequency of the further resonator with an optical resonant frequency of the resonator until the measured output light intensity is at the predefined value, determining the change in the effective refractive index of the resonator based on the change in the current or voltage applied to the further resonator.

BRIEF DESCRIPTION OF THE DRAWINGS

In the drawings, like reference characters generally refer to the same parts throughout the different views. The drawings are not necessarily to scale, emphasis instead generally being placed upon illustrating the principles of the invention. In the following description, various embodiments of the invention are described with reference to the following drawings, in which:

FIG. **1**A shows a schematic block diagram of an optical sensing system, according to various embodiments.

FIG. **1**B shows a schematic block diagram of an optical sensing system, according to various embodiments.

FIG. **2** shows a flow chart illustrating a method of determining a change in an effective refractive index of a resonator of an optical sensing system, according to various embodiments.

FIG. **3**A shows a schematic view of an optical sensing system, according to various embodiments.

FIG. **3**B shows a schematic view of an optical sensing system, according to various embodiments.

FIG. **3**C shows a schematic view of an optical sensing system, according to various embodiments.

FIG. **4** shows plots of optical resonances of the optical sensing system of various embodiments, illustrating the working principle of the optical sensing system.

FIG. **5** shows a plot of the transmission spectra as a function of current change of an optical sensing system, according to various embodiments.

FIGS. **6**A through **6**C show results of numerical simulations for calculating the sensing sensitivity for a channel waveguide structure on silicon-on-insulator (SOI).

FIG. **7**A shows a plot of normalized intensity as a function of wavelength shift for different radii of a microring resonator, according to various embodiments.

FIG. **7**B shows a plot of quality factor as a function of microring radius for different coupling coefficients, according to various embodiments.

FIG. **7**C shows a plot of normalized intensity as a function of microring radius for different coupling coefficients, according to various embodiments.

DETAILED DESCRIPTION

The following detailed description refers to the accompanying drawings that show, by way of illustration, specific details and embodiments in which the invention may be practiced. These embodiments are described in sufficient detail to enable those skilled in the art to practice the invention. Other embodiments may be utilized and structural, logical, and electrical changes may be made without departing from the scope of the invention. The various embodiments are not necessarily mutually exclusive, as some embodiments can be combined with one or more other embodiments to form new embodiments.

Embodiments described in the context of one of the methods or devices are analogously valid for the other method or device. Similarly, embodiments described in the context of a method are analogously valid for a device, and vice versa.

In the context of various embodiments, the phrase "at least substantially" may include "exactly" and a variance of +/−5% thereof. As an example and not limitations, "A is at least substantially same as B" may encompass embodiments where A is exactly the same as B, or where A may be within a variance of +/−5%, for example of a value, of B, or vice versa.

In the context of various embodiments, the term "about" or "approximately" as applied to a numeric value encompasses the exact value and a variance of +/−5% of the value.

As used herein, the term "and/or" includes any and all combinations of one or more of the associated listed items.

Various embodiments relate to the fields of silicon nano/micro-photonics and/or optical biological/chemical sensing.

Various embodiments provide an optical sensing system, for example a microring resonator-based optical sensor or sensing system. The optical sensing system may be a biological/chemical sensor. In various embodiments, the optical sensing system includes serial-cascaded dual-microring resonators, where one of the microring resonators serves as a sensing element while the other microring resonator serves as a tracing element. In other words, the optical sensing system of various embodiments is a dual-microring resonator-based optical sensing system, which may include identically designed add-drop microring resonators, where one microring resonator (e.g. sensing resonator or sensing element) may be used for sensing while the other microring resonator (e.g. tracing resonator or tracing element) may be used for tracing, for example for tracking or responding to any changes in the properties, e.g. effective refractive index, of the sensing resonator. The tracing resonator may be integrated with the sensing resonator and may function as a microring filter to determine the resonance wavelength shift of the sensing resonator. The optical sensing system of various embodiments may provide a Lorentz filter response.

In various embodiments, the sensing resonator may have an optical shift or change and the tracing resonator may be tuned, for example electrically tuned by applying a current or a voltage, to shift its optical properties so as to match the optical shift of the sensing resonator. The electrical tuning may result in an increased output signal detected. Based on the electrical tuning, the output signal level may then be converted to a sensing level. In other words, the sensing level may be determined as a function of the output signal level.

In various embodiments, the sensing resonator may sense a shift or change in its resonance wavelength due to a change in its effective refractive index, for example due to or in response to one or more stimuli, while the tracing resonator, which is tunable, traces the resonance wavelength shift due to the change in the effective refractive index of the sensing resonator. In various embodiments, the change in the effective refractive index of the sensing resonator may be due to a change in the refractive index of the cladding (e.g. upper cladding layer) of the sensing resonator. In various embodiments, by providing the tracing resonator and incorporating thermo-optical tuning or electro-optical tuning with the tracing resonator (e.g. the tracing resonator may be dynamically thermally tuned or electrically tuned, due to thermo-optic (TO) or electro-optic (EO) effect respectively, (e.g. free carrier dispersion effect, liquid crystal tuning, polymer tuning)), the resonance wavelength shift may be obtained or determined, for example, by directly reading or determining the current or voltage applied to the tracing resonator, and/or changes in the current or voltage applied. The current or voltage may be applied using a voltage/current supply source. For TO tuning, the tracing resonator includes a thermal heater, and the resonance wavelength shift may be obtained or determined, for example, by directly reading or determining the current or voltage applied to the thermal heater of the tracing resonator, and/or changes in the current or voltage applied.

In various embodiments of the optical sensing system, the sensing interrogation may be the detection of the maximum intensity (e.g. power), based on the filter-cascading effect of the sensing resonator and the tracing resonator.

The optical sensing system of various embodiments does not require the use of a wavelength-scanning method for sensing interrogation which requires advanced instruments and which are unsuitable for portable application, thereby providing cost-effective optical sensing (e.g. optical biological/chemical sensing) and potential point-of-care applications, e.g. biomedical applications. Therefore, the optical sensing system of various embodiments eliminates or does not require the usage of high-resolution wavelength-tunable lasers, thus significantly lowering the cost.

FIG. **1**A shows a schematic block diagram of an optical sensing system **100**, according to various embodiments. The optical sensing system **100** includes a resonator arrangement **102** including a first resonator **104**, wherein an effective refractive index of the first resonator **104** is changeable in response to a change in a refractive index of a cladding (e.g. upper cladding) of the first resonator **104**, and a second resonator **106** to which a current or voltage being adjustable in response to a change in the effective refractive index of the first resonator **104** is applied, wherein the optical sensing system **100** is configured to determine the change in the effective refractive index of the first resonator **104** based on a change in the current or voltage applied to the second resonator **106**. In the context of various embodiments, the light may be broadband or wideband.

In other words, the refractive index of the cladding (e.g. the cladding or upper cladding of the first resonator **104** that may be exposed to a stimulus) of the first resonator **104** may change, for example in response to a stimulus, for example a sample or fluid which may come in contact with the cladding, e.g. for sensing applications. The change in the refractive index of the cladding of the first resonator **104** may result in a change in the effective refractive index of the first resonator **104**. A current or a voltage may be applied to the second resonator **106**, and the current or the voltage may be adjusted in response to the change in the effective refractive index of the first resonator **104**. The optical sensing system **100** may then determine the change in the effective refractive index of the first resonator **104** based on a change in the current or voltage applied to the second resonator **106**.

In FIG. **1**A, the line represented as **108** is illustrated to show the relationship between the first resonator **104** and the second resonator **106**, which may include electrical coupling and/or mechanical coupling and/or optical coupling.

FIG. **1**B shows a schematic block diagram of an optical sensing system **120**, according to various embodiments. The optical sensing system **120** includes a resonator arrangement **102** including a first resonator **104** and a second resonator **106**, which may be similar to the embodiment as described in the context of FIG. **1**A.

In various embodiments, the second resonator **106** includes a thermal heater **160**, and wherein a current or voltage being adjustable in response to a change in the effective refractive index of the first resonator **104** is applied to the thermal heater **160**, wherein the optical sensing system **120** is configured to

determine the change in the effective refractive index of the first resonator **104** based on a change in the current or voltage applied to the second resonator **106** (i.e. a change in the current or voltage applied to the thermal heater **160**). In various embodiments, the thermal heater **160** may be integrated with the second resonator **106**. In various embodiments, the optical sensing system **120** may include a thermal heater configured to supply heat to the second resonator **106** (e.g. thermally coupled to the second resonator **106**).

The optical sensing system **120** may further include a light source **122** configured to provide light. In the context of various embodiments, the light source **122** may be or may include a broadband light source, including but not limited to a white light source, a halogen lamp, a light emitting diode (LED) and a light source providing amplified spontaneous emission (ASE).

The optical sensing system **120** may further include an input optical waveguide **124** configured to guide received light, wherein the resonator arrangement **102** may be coupled to the input optical waveguide **124** to receive the light from the input optical waveguide **124**. In various embodiments, the input optical waveguide **124** may be coupled, for example optically coupled and/or mechanically coupled, to the light source **122** to receive light from the light source **122** and guide the light to the resonator arrangement **102**.

The optical sensing system **120** may further include a coupling optical waveguide **126** coupled between the first resonator **104** and the second resonator **106**, the coupling optical waveguide **126** being configured to guide light received from the first resonator **104** to the second resonator **106** or from the second resonator **106** to the first resonator **104**. Therefore, in various embodiments, the first resonator **104** is indirectly coupled to the second resonator **106**, or vice versa, via the coupling optical waveguide **126**.

In various embodiments, as the coupling optical waveguide **126** is coupled between the first resonator **104** and the second resonator **106**, the first resonator **104** is indirectly coupled to the second resonator **106**, or vice versa, via the coupling optical waveguide **126**. As the first resonator **104** and the second resonator **106** are two different or separate structures, and which may be independent from each other, the first resonator **104** and the second resonator **106** have their respective spectral responses. By indirectly coupling the first resonator **104** and the second resonator **106** via the coupling optical waveguide **126**, the tracing function (i.e. where one resonator may track the optical resonance shift of the other resonator) may be carried out.

The optical sensing system **120** may further include an output optical waveguide **128** coupled to the resonator arrangement **102**, the output optical waveguide **128** being configured to output light received from the resonator arrangement **102**.

The optical sensing system **120** may further include a detector **130** coupled to the output optical waveguide **128**, wherein the detector **130** is configured to receive light from the output optical waveguide **128**. In the context of various embodiments, the detector **130** may be or may include a photodetector, for example a silicon-germanium (SiGe) photodetector or a hybrid III-V-on-silicon photodetector. As used herein with respect to the photodetector, the term "III" refers to Group III elements (e.g. aluminum, gallium) and the term "V" refers to Group V elements (e.g. phosphorus, antimony).

The detector **130** may be configured to measure an intensity of light received from the output optical waveguide **128**. In various embodiments, the intensity of light may be maximum when an optical resonant frequency of the first resonator **104** and an optical resonant frequency of the second resonator **106** are aligned. In other words, the intensity of light may be maximum when the optical resonant frequency (or resonant wavelength) of the first resonator **104** and the optical resonant frequency (or resonant wavelength) of the second resonator **106** are at least substantially same. In various embodiments, the optical resonant frequency of the first resonator **104** may change in response to the change in the effective refractive index of the first resonator **104**. In various embodiments, the optical sensing system **120** may be configured to change the current or voltage applied to the second resonator **106** to align the optical resonant frequency of the second resonator **106** with the changed optical resonant frequency of the first resonator **104** such that the intensity of light measured by the detector **130** may be maximum.

In various embodiments, the first resonator **104** may be coupled to the input optical waveguide **124** and the coupling optical waveguide **126**, and the second resonator **106** may be coupled to the output optical waveguide **128** and the coupling optical waveguide **126**. The first resonator **104** may have an input port **140** coupled to the input optical waveguide **124** and an output port **142** coupled to the coupling optical waveguide **126**, wherein the first resonator **104** may be configured to receive light from the input optical waveguide **124** via the input port **140**, direct the light to the output port **142**, and transmit the light to the coupling optical waveguide **126** via the output port **142**. The second resonator **106** may have an input port **144** coupled to the coupling optical waveguide **126** and an output port **146** coupled to the output optical waveguide **128**, wherein the second resonator **106** may be configured to receive light from the coupling optical waveguide **126** via the input port **144**, direct light from the input port **144** to the output port **146**, and transmit the light to the output optical waveguide **128** via the output port **146**.

In various embodiments, the second resonator **106** may be coupled to the input optical waveguide **124** and the coupling optical waveguide **126**, and the first resonator **104** may be coupled to the output optical waveguide **128** and the coupling optical waveguide **126**. The second resonator **106** may have an input port **144** coupled to the input optical waveguide **124** and an output port **146** coupled to the coupling optical waveguide **126**, wherein the second resonator **106** may be configured to receive light from the input optical waveguide **124** via the input port **144**, direct the light to the output port **146**, and transmit the light to the coupling optical waveguide **126** via the output port **146**. The first resonator **104** may have an input port **140** coupled to the coupling optical waveguide **126** and an output port **142** coupled to the output optical waveguide **128**, wherein the first resonator **104** may be configured to receive light from the coupling optical waveguide **126** via the input port **140**, direct light from the input port **140** to the output port **142**, and transmit the light to the output optical waveguide **128** via the output port **142**.

In FIG. **1**B, the lines represented as **150**, **152**, **154** are illustrated to show the relationship between the different features or components, which may include electrical coupling and/or mechanical coupling and/or optical coupling.

In the context of various embodiments, the first resonator **104** and the second resonator **106** may be identical. This means that the first resonator **104** and the second resonator **106** may have at least substantially similar or identical parameters, for example in terms of the structure, configuration, shape (e.g. ring-shaped, e.g. circular or elliptical) and dimensions (e.g. radius). In various embodiments, having identical or identically designed first resonator **104** and second resonator **106** may mean that the respective optical resonances, e.g. the respective resonant wavelengths (or resonant frequencies) of first resonator **104** and the second resonator **106**

may be at least substantially aligned. The respective resonant wavelengths may be at least substantially aligned at the initial state of the optical sensing system **100** when not in operation, and the resonant wavelength of one of the resonators may be tuned, for example via electro-optic or thermo-optic effect, so as to at least substantially align with the resonant wavelength of the other resonator which may have shifted as a response to a stimulus during sensing operation.

In the context of various embodiments, each of the first resonator **104** and the second resonator **106** may include or may be a closed loop. Each closed loop may be ring-shaped, for example including circular or elliptical shapes. In various embodiments, each of the first resonator **104** and the second resonator **106** is a ring (e.g. microring) resonator or a microresonator. However, it should be appreciated that other resonators, including but not limited to microdisk and Fabry-Perot cavity/resonator may also be used for the first resonator **104** and/or the second resonator **106**.

In the context of various embodiments, the first resonator **104** and the second resonator **106** may be independent from each other. For example, either one of the first resonator **104** or the second resonator **106** may be employed for optical sensing, while the other resonator may be employed for tracing.

In the context of various embodiments, one or more electrical interconnections (e.g. wire or bus) may be connected to either the first resonator **104** or the second resonator **106**, acting as the tracing resonator, for the application of a current (or a voltage). The first resonator and/or the second resonator may also include electrodes for the application of a current (or a voltage).

In the context of various embodiments, the term "resonator" may mean a component, a device or a system that exhibits resonance, where the device may oscillate or resonate at relatively larger amplitudes at particular frequencies, known as its resonant frequencies, compared to the amplitudes of the oscillations at non-resonant frequencies.

In the context of various embodiments, the cladding of the first resonator **104** may include or may be an oxide cladding, for example SiO_2 or InAlAs oxide ($InAlAs(O_x)$). The cladding may be formed using a CMOS-compatible fabrication process, for providing a cost effective optical sensing system.

In the context of various embodiments, the "effective refractive index" depends on the overall waveguide or resonator configuration, for example as a function of the refractive index of the core and the refractive index of the cladding of the waveguide or resonator.

FIG. **2** shows a flow chart **200** illustrating a method of determining a change in an effective refractive index of a resonator of an optical sensing system, according to various embodiments.

At **202**, it is determined if an output light intensity measured by a detector of the optical sensing system is at a predefined value. In other words, an output light intensity measured by a detector of the optical sensing system is determined as to whether the output light intensity is at a predefined value (e.g. a maximum value or intensity).

At **204**, if the measured output light intensity is not at the predefined value, a current or voltage applied to a further resonator of the optical sensing system is adjusted to align an optical resonant frequency of the further resonator with an optical resonant frequency of the resonator until the measured output light intensity is at the predefined value.

At **206**, the change in the effective refractive index of the resonator is determined based on the change in the current or voltage applied to the further resonator.

In various embodiments, the change in the effective refractive index of the resonator and the change in the current applied to the further resonator has a relationship of

$$\Delta n_{eff} = 2ARI\Delta I\frac{n_g}{\lambda_0},$$

where Δn_{eff} is the change in the effective refractive index of the resonator, A is thermal efficient (nm/W), R is the resistance of a thermal heater, I is the current applied to the further resonator, ΔI is the change in the current applied to the further resonator, n_g is a group refractive index of the resonator, and λ_0 is the center wavelength of the resonator. In various embodiments, the further resonator includes the thermal heater.

In various embodiments, the method of determining a change in an effective refractive index of a resonator (e.g. a sensing resonator) of an optical sensing system may include receiving an optical signal (e.g. light) via an input optical waveguide, which then passes or couples a portion of the optical signal to the resonator (e.g. first resonator), coupling the optical signal from the resonator (e.g. optical signal that is dropped from the resonator) to a coupling optical waveguide, which then passes or couples a portion of the optical signal to a further resonator (e.g. second resonator), coupling the optical signal (e.g. optical signal that is dropped from the further resonator) from the further resonator (e.g. a tracing resonator) to an output optical waveguide, and receiving or detecting the optical signal from the output optical waveguide by a detector. A variable current (or a variable voltage) may be applied to the further resonator to tune a suitable parameter (e.g. optical resonant frequency) of the further resonator to achieve a predefined value (e.g. maximum intensity) of the output signal detected by the detector. The change in the current or voltage applied to the further resonator so as to achieve the predefined value of the detected optical signal may be determined in order to determine the corresponding change in the effective refractive index of the resonator (e.g. sensing resonator).

In the context of various embodiments, it should be appreciated that the first resonator (e.g. **104**) and the second resonator (e.g. **106**) are interchangeable. In other words, depending on the configuration of the optical sensing system (e.g. **100**) or the resonator arrangement (e.g. **102**), each of the first resonator (e.g. **104**) and the second resonator (e.g. **106**) may act as either a sensing resonator or a tracing resonator. The sensing resonator may be a passive element while the tracing resonator may be an active element, where a current or a voltage is applied.

In the context of various embodiments, the optical signal or light of interest that is detected by the detector, includes the light that is dropped from one resonator (e.g. the first resonator) which is then coupled to another resonator (e.g. the second resonator), and subsequently the light that is dropped by the other resonator (e.g. the second resonator). Therefore, the detector detects light that is dropped from two resonators.

In various embodiments, light may be coupled, for example from a waveguide, to a ring or microring resonator. Oscillation modes (with spatial wavelength) light may be coupled to the ring resonator and may propagate in the ring resonator, such that the oscillation modes may be lost, for example via a through port or a drop port. Some of the wavelength light, which does not satisfy the resonant condition (i.e. not resonant wavelength) may be passed 'through' by the ring resonator directly with a small loss and output

from the through port. From the through port, oscillation modes show a valley-like shape in the spectrum. While the oscillation modes propagate in the ring resonator, in each propagation through a revolution of the ring resonator, a part of the light, which satisfies the resonant condition (i.e. light of the resonant wavelength) may be dropped from the ring resonator and output through the drop port. From the drop port, oscillation modes show a peak in the spectrum. In the drop port, only oscillation modes of resonant wavelength are present.

Various embodiments may provide a silicon microring resonator-based optical sensing system employing a dual-microring resonator structure, which may include two identically designed microring resonators. The dual-microring resonator optical sensing system employs the filter-cascading effect and enable the use of a broadband light source, thus significantly decreasing the cost.

Various embodiments of the optical sensing system, as compared to conventional devices employing wavelength-scanning method, may provide the following advantages: 1) the use of broadband light source inputs, rather than high-resolution wavelength tunable laser inputs, 2) voltage/current scanning with maximum intensity detection, instead of wavelength scanning, 3) sensing interrogation involving voltage/current change direct readout, rather than the detection of resonance wavelength shift, 4) narrowed resonance linewidth as a result of the filter-cascading effect, thus enhancing the sensing sensitivity, and 5) the detection limit is determined by the resolution of the voltage/current supply source, rather than the tunable laser resolution. In addition, the use of a broadband light source rather than a high-resolution wavelength-tunable laser reduces the cost. Furthermore, the optical sensing system of various embodiments has a compact footprint and may be integrated (e.g. planar integration) with CMOS-compatible fabrication process.

The optical sensing system of various embodiments may be used in various application including medical diagnosis, healthcare and environmental monitoring, amongst others.

FIG. **3**A shows a schematic view of an optical sensing system **300**, according to various embodiments. The optical sensing system **300** is a microring-resonator-based optical sensing system, having two microring resonators separately for optical sensing and tracing. In various embodiments, the two microring resonators may be identically designed.

The optical sensing system **300** includes a resonator arrangement including a sensing microring (sensing resonator) **302** and a tracing microring (tracing resonator) **304**. An effective refractive index of the sensing resonator **302** may be changeable in response to a change in a refractive index of a cladding (e.g. upper cladding layer) of the sensing resonator **302**. A current or a voltage being adjustable in response to a change in the effective refractive index of the sensing resonator **302** may be applied to the tracing resonator **304**, wherein the optical sensing system **300** may be configured to determine the change in the effective refractive index of the sensing resonator **302** based on a change in the current or voltage applied to the tracing resonator **304**. The sensing resonator **302** may have a resonant wavelength, λ_s, while the tracing resonator **304** may have a resonant wavelength, λ_t. Where the sensing resonator **302** and the tracing resonator **304** are identical, λ_s is at least substantially equal to λ_t, at the original or initial state of the optical sensing system **300**.

The optical sensing system **300** further includes a coupling optical waveguide **306** coupled between the sensing resonator **302** and the tracing resonator **304**, where the coupling optical waveguide **306** is configured to guide light received from the sensing resonator **302** to the tracing resonator **304**.

The optical sensing system **300** may further include an input optical waveguide **308** configured to guide received light (e.g. an input light), for example an optical signal or light, as represented by the arrow **310**, for example from a wideband or broadband source **312**. The input light **310** may be broadband, having a spectrum **332** covering a range of wavelengths. As shown in FIG. **3**A, the sensing resonator **302** is coupled to the input optical waveguide **308** to receive the light **310** from the input optical waveguide **308**.

The optical sensing system **300** may further include an output optical waveguide **314** coupled to the tracing resonator **304**, the output optical waveguide **314** being configured to output light received from the resonator arrangement or the tracing resonator **304**.

As illustrated in FIG. **3**A, a portion of the input light **310** may pass through the sensing resonator **302**, as represented by the arrow **316**, and is outputted to a through port, and a portion of the input light **310** may be coupled to the sensing resonator **302**, which may propagate and cycle through and within the sensing resonator **302**, where part of the light, as represented by the arrow **318**, may be dropped and coupled to the coupling optical waveguide **306**. The light **318** may have a spectrum **334** having a peak wavelength corresponding at least substantially to λ_s. Therefore, the sensing resonator **302** may function as a microring filter. During sensing operation where the effective refractive index of the sensing resonator **302** is changed, the optical resonance of the sensing resonator **302** is changed, thereby changing or shifting the resonant wavelength λ_s to $\lambda_{s'}$.

A portion of the light **318** may pass through the tracing resonator **304**, as represented by the arrow **320**, and is outputted to a through port, and a portion of the light **318** may be coupled to the tracing resonator **304**, which may propagate and cycle through and within the tracing resonator **304**, where part of the light, as represented by the arrow **322**, may be dropped and coupled to the output optical waveguide **314**. The light **322** may then be outputted to a detector **324** coupled to the output optical waveguide **314** to measure an intensity of the light **322** received from the output optical waveguide **314**.

The light **322** may have a spectrum **336** with a reduced intensity, resulting from the misalignment of the respective optical resonances of the sensing resonator **302** and the tracing resonator **304**. For example, during sensing operation, the resonant wavelength of the sensing resonator may have been shifted to $\lambda_{s'}$, which is not aligned with λ_t, thereby resulting in spectrum **336** with a reduced intensity. In order to increase or maximise the intensity, the optical resonance of the tracing resonator **304** may be tuned via electro-optic or thermo-optic effect to shift the resonant wavelength λ_t to $\lambda_{t'}$, such that $\lambda_{t'}$ is at least substantially equal to $\lambda_{s'}$, as a result of a change in the refractive index or effective refractive index of the tracing resonator **304**.

The square box **330** illustratively show the sensing window of the optical sensing system **300**, for sensing stimuli or constituents of a sample, for example a biological sample and/or a chemical sample.

Each of the input optical waveguide **308**, the coupling optical waveguide **306** and the output optical waveguide **314** may be an at least substantially straight waveguide. However, it should be appreciated that each of the input optical waveguide **308**, the coupling optical waveguide **306** and the output optical waveguide **314** may have other configurations, for example a bend waveguide. Furthermore, each of the input optical waveguide **308**, the coupling optical waveguide **306** and the output optical waveguide **314** may have different configurations.

In various embodiments, the sensing resonator **302** acts as a sensing element to sense a change in the effective refractive index of the sensing resonator **302**, which may result in a shift in the resonance wavelength of the sensing resonator **302**. The tracing resonator **304** acts as a tracing element to trace the resonance wavelength shift of the sensing resonator **302** due to the refractive index change, by either thermo-optic (TO) or electro-optic (EO) effect. The drop-port transmission (e.g. **318**) from the sensing resonator **302** feeds to the tracing resonator **304**, and the drop-port output (e.g. **322**) from the tracing resonator **304** is monitored. In embodiments where the tracing resonator **304** traces the resonance wavelength shift of the sensing resonator **302** by thermo-optic (TO) effect, the tracing resonator **304** includes a thermal heater. A current or voltage is applied to the tracing resonator **304** (e.g. to the thermal heater) to increase the temperature of the tracing resonator **304** so as to tune the optical resonance of the tracing resonator **304**.

While FIG. **3**A shows that the sensing resonator **302** is coupled to the input optical waveguide **308** and the coupling optical waveguide **306**, and that the tracing resonator **304** is coupled to the coupling optical waveguide **306** and the output optical waveguide **314**, it should be appreciated that the positions of the sensing resonator **302** and the tracing resonator **304** may be interchangeable such that the sensing resonator **302** is coupled to the coupling optical waveguide **306** and the output optical waveguide **314** and the tracing resonator **304** is coupled to the input optical waveguide **308** and the coupling optical waveguide **306**.

FIG. **3**B shows a schematic view of an optical sensing system **350**, according to various embodiments. The optical sensing system **300** includes a resonator arrangement including a sensing resonator **352** and a tracing resonator **354**. The optical sensing system **350** further includes a coupling optical waveguide **356** coupled between the sensing resonator **352** and the tracing resonator **354**, where the coupling optical waveguide **356** is configured to guide light received from the tracing resonator **354** to the sensing resonator **352**.

The optical sensing system **350** may further include an input optical waveguide **358** configured to guide an input optical signal or light, for example from a wideband or broadband source **366**. The input optical waveguide **358** is coupled to the tracing resonator **354**. The optical sensing system **350** may further include an output optical waveguide **360** coupled to the sensing resonator **352**, the output optical waveguide **360** being configured to output light received from the resonator arrangement or the sensing resonator **352** to a detector, for example an optical power meter **368**.

The sensing resonator **352**, the tracing resonator **354**, the input optical waveguide **358**, the coupling optical waveguide **356** and the output optical waveguide **360** may be formed or fabricated on a substrate, for example a silicon chip (Si-chip) **374**.

Features, elements or components of the optical sensing system **350** that are similarly present in the optical sensing system **300** (FIG. **3**A) may be as described in the context of the optical sensing system **300**.

Each of the input optical waveguide **358**, the coupling optical waveguide **356** and the output optical waveguide **360** may be a bend waveguide. However, it should be appreciated that each of the input optical waveguide **358**, the coupling optical waveguide **356** and the output optical waveguide **360** may have other configurations, for example a straight waveguide. Furthermore, each of the input optical waveguide **358**, the coupling optical waveguide **356** and the output optical waveguide **360** may have different configurations.

In various embodiments, the sensing resonator **352** acts as a sensing element to sense a change in the effective refractive index of the sensing resonator **352**, for example in response to a stimulus, which may result in a shift in the resonance wavelength of the sensing resonator **352**. The tracing resonator **354** acts as a tracing element to trace the resonance wavelength shift of the sensing resonator **352** due to the refractive index change, by either thermo-optic (TO) or electro-optic (EO) effect. The drop-port transmission, as represented by the arrow **370**, from the tracing resonator **354** feeds to the sensing resonator **352**, and the drop-port output, as represented by the arrow **372**, from the sensing resonator **352** is monitored by the optical power meter **368**. In embodiments where the tracing resonator **354** traces the resonance wavelength shift of the sensing resonator **352** by thermo-optic (TO) effect, the tracing resonator **354** includes a thermal heater. A current or voltage is applied to the tracing resonator **354** (e.g. to the thermal heater) to increase the temperature of the tracing resonator **354** so as to tune the optical resonance of the tracing resonator **354**.

While FIG. **3**B shows that the tracing resonator **354** is coupled to the input optical waveguide **358** and the coupling optical waveguide **356**, and that the sensing resonator **352** is coupled to the coupling optical waveguide **356** and the output optical waveguide **360**, it should be appreciated that the positions of the sensing resonator **352** and the tracing resonator **354** may be interchangeable such that the tracing resonator **354** is coupled to the coupling optical waveguide **356** and the output optical waveguide **360** and the sensing resonator **352** is coupled to the input optical waveguide **358** and the coupling optical waveguide **356**.

FIG. **3**C shows a schematic view of an optical sensing system **380**, according to various embodiments. The optical sensing system **380** includes a resonator arrangement including a sensing resonator **382** and a tracing resonator **384**. The optical sensing system **380** further includes a coupling optical waveguide **386** coupled between the sensing resonator **382** and the tracing resonator **384**, where the coupling optical waveguide **386** is configured to guide light received from the sensing resonator **382** to the tracing resonator **384**.

The optical sensing system **380** may further include an input optical waveguide **388** configured to guide an input optical signal or light, for example from a wideband or broadband source (not shown). The input optical waveguide **388** is coupled to the sensing resonator **382**. The optical sensing system **380** may further include an output optical waveguide **390** coupled to the tracing resonator **384**, the output optical waveguide **390** being configured to output light received from the resonator arrangement or the tracing resonator **384** to a detector (not shown).

The optical sensing system **380** or the tracing resonator **384** may further include a heater or a thermal heater (e.g. a micro-heater) **392** including a pair of electrodes **394** formed or arranged in proximity to the tracing resonator **384**, for example over the tracing resonator **384**. The thermal heater **392** may be employed to supply heat to the tracing resonator **384** to change the refractive index or effective refractive index of the tracing resonator **384** for tracing the effective refractive index change of the sensing resonator **382**, as a result of TO effect. However, it should be appreciated that in embodiments of optical sensing system **380** employing the EO effect, the thermal heater **392** may not be in operation or the tracing resonator **384** may not include the thermal heater **392**.

Features, elements or components of the optical sensing system **380** that are similarly present in the optical sensing system **300** (FIG. **3**A) and/or optical sensing system **350**

(FIG. **3**B) may be as described in the context of the optical sensing system **300** and/or optical sensing system **350**.

Each of the input optical waveguide **388**, the coupling optical waveguide **386** and the output optical waveguide **390** may be a bend waveguide. However, it should be appreciated that each of the input optical waveguide **388**, the coupling optical waveguide **386** and the output optical waveguide **390** may have other configurations, for example a straight waveguide. Furthermore, each of the input optical waveguide **388**, the coupling optical waveguide **386** and the output optical waveguide **390** may have different configurations.

In various embodiments, the sensing resonator **382** acts as a sensing element to sense a change in the effective refractive index of the sensing resonator **382**, for example in response to a stimulus, which may result in a shift in the resonance wavelength of the sensing resonator **382**. The tracing resonator **384** acts as a tracing element to trace the resonance wavelength shift of the sensing resonator **382** due to the refractive index change, by either thermo-optic (TO) or electro-optic (EO) effect.

In various embodiments, an optical signal or light may be provided to port **1** of the coupling optical waveguide **386** and the light from port **1'** of the output optical waveguide **390** may be monitored to determine the 'drop' status of the tracing resonator **384**. A portion of the light from port **1** is coupled via the coupling optical waveguide **386** to the tracing resonator **384**, where a portion of the light coupled into the tracing resonator **384** is dropped via the output optical waveguide **390** to port **1'**.

In various embodiments, an optical signal or light may be provided to port **3** of the input optical waveguide **388** and the light from port **3'** of the coupling optical waveguide **386** may be monitored to determine the 'drop' status of the sensing resonator **382**. A portion of the light from port **3** is coupled via the input optical waveguide **388** to the sensing resonator **382**, where a portion of the light coupled into the sensing resonator **382** is dropped via the coupling optical waveguide **386** to port **3'**.

In various embodiments, an optical signal or light may be provided to port **1** of the coupling optical waveguide **386** and the light from port **3'** of the coupling optical waveguide **386** may be monitored to determine the 'through' status of the tracing resonator **384** and the sensing resonator **382**. A portion of the light from port **1** passes through the tracing resonator **384** and the sensing resonator **382** via the coupling optical waveguide **386** to port **3'**.

In various embodiments, an optical signal or light may be provided to port **3** of the input optical waveguide **388** and the light from port **1'** of the output optical waveguide **390** may be monitored to determine the 'through' status of the sensing resonator **382** and the tracing resonator **384**. A portion of the light from port **3** passes through the sensing resonator **382** via the coupling optical waveguide **386** to the tracing resonator **384**, where a portion of the light coupled into the tracing resonator **384** passes through via the output optical waveguide **390** to port **1'**.

In various embodiments, an optical signal or light may be provided to port **2** of the input optical waveguide **388** and the light from port **2'** of the output optical waveguide **390** may be monitored for sensing a target or a sample. A portion of the light from port **2** is dropped from the sensing resonator **382** and couples via the coupling optical waveguide **386** to the tracing resonator **384**, where a portion of the light coupled into the tracing resonator **384** is dropped via the output optical waveguide **390** to port **2'**. A detector may be provided at port **2'** to detect the optical signal or light received, after target sensing.

While FIG. **3**C shows that the sensing resonator **382** is coupled to the input optical waveguide **388** and the coupling optical waveguide **386**, and that the tracing resonator **384** is coupled to the coupling optical waveguide **386** and the output optical waveguide **390**, it should be appreciated that the positions of the sensing resonator **382** and the tracing resonator **384** may be interchangeable such that the sensing resonator **382** is coupled to the coupling optical waveguide **386** and the output optical waveguide **390** and the tracing resonator **384** is coupled to the input optical waveguide **388** and the coupling optical waveguide **386**.

FIG. **4** shows plots **400**, **420**, **440**, of optical resonances of the optical sensing system of various embodiments, illustrating the working principle of the optical sensing system, based on the filter-cascading effect. As a result of the filter-cascading effect for a dual microring-cascaded system, the maximum output intensity occurs when the respective resonances of the two microrings (e.g. the sensing resonator and the tracing resonator) are aligned. In other words, the maximum output intensity occurs when the two microring resonators have at least substantially similar resonant wavelength or resonant frequency.

In various embodiments, the two microring resonators may be identical. In the original or initial state, the optical resonances for the two identically designed microring resonators may be at least substantially aligned with each other. As shown in the plot **400**, the optical resonance **402** of the sensing resonator (sensing ring) and the optical resonance **404** of the tracing resonator (tracing ring) are aligned with each other, at an at least substantially similar resonant wavelength. Therefore, the intensity of the output **406** from the optical sensing system may be at a maximum.

When the sensing resonator is employed for sensing, the refractive index of the cladding of the sensing resonator may change as a response to a stimulus, thereby changing the effective refractive index of the sensing resonator. As shown in the plot **420**, after sensing, the resonance **402** of the sensing resonator may be red-shifted (i.e. the resonant wavelength is shifted to a longer wavelength), while the resonance **404** of the tracing resonator may remain at the original state, thus resulting in a decrease in the intensity of the output **406** of the optical sensing system. Therefore, the resonant wavelength change, $\Delta\lambda$, of the sensing resonator is due to an effective refractive index change of the sensing resonator, as a result of a refractive index change of the cladding of the sensing resonator. In plot **420**, Δn refers to the change in the effective refractive index change of the sensing resonator.

Subsequently, electro-optic (EO) effect or thermo-optic (TO) effect may be employed to red-shift the resonance of the tracing resonator in order to increase the output intensity of the optical sensing system, for example to the maximum intensity. As shown in the plot **440**, for example after TO tuning, the resonance **404** of the tracing resonator may be red-shifted to at least substantially align with the resonance **402** of the sensing resonator, thus resulting in an increase in the intensity of the output **406** of the optical sensing system, for example to maximum intensity. In addition, the filter-cascading effect narrows the resonance linewidth of the output **406**, thereby enhancing the sensing sensitivity.

Examples and results as described hereinafter is based on thermo-optic (TO) effect, as an example and for illustrative purposes. However it should be appreciated that both EO and TO tunings or effects may be realized by supplying a current or voltage to the tracing resonator, although using different mechanisms. Using EO tuning, the current or voltage is applied to the tracing resonator (e.g. p-n/p-i-n diode) to generate free carriers, thus changing the refractive index or effec-

tive refractive index of the tracing resonator so as to change the optical resonance of the tracing resonator. Using TO tuning, the current or voltage is applied to the tracing resonator, e.g. to a thermal heater of the tracing resonator to generate heat, thus changing the temperature of the tracing resonator, thereby changing the refractive index or effective refractive index of the tracing resonator so as to change the optical resonance of the tracing resonator. Therefore, the results obtained using the EO effect or the TO effect may be at least substantially similar. However, there may be a difference in terms of the resonance shift, for example the amount of resonance shift.

As an example for employing TO tuning, variable power may be applied to the tracing resonator (i.e. to the thermal heater of the tracing resonator) to tune the optical resonance of the tracing resonator. Therefore, the resonant wavelength change, $\Delta\lambda$, of the tracing resonator may be due to a power change, ΔW, applied to the tracing resonator, for effecting thermo-optic tuning of the tracing resonator. Hence, by reading or determining the power supplied to the tracing resonator (e.g. to the thermal heater), the effective refractive index change of the sensing resonator may be determined.

In various embodiments, A) may be proportional to Δn (i.e. $\Delta\lambda \propto \Delta n$) and $\Delta\lambda$ may be proportional to ΔW (i.e. $\Delta\lambda \propto \Delta W$). Therefore, Δn may be proportional to ΔW (i.e. $\Delta n \propto \Delta W$).

In various embodiments, the change in the power, ΔW, supplied to the tracing resonator may be determined by scanning the voltage or current supplied so as to determine the transmission spectrum or output spectrum of the optical sensing system according to the change in the voltage or current. FIG. **5** shows a plot **500** of the transmission spectra as a function of current change of an optical sensing system, according to various embodiments, illustrating the transmission spectrum **502** before optical sensing and the transmission spectrum **504** after optical sensing. The plot **500** may be obtained by numerical analysis.

As illustrated in the plot **500**, the refractive index change Δn, for example the change in the effective refractive index change of the sensing resonator, may be determined by reading out or determining the current change $\Delta I(\Delta n)$ from the spectrum **504**. In addition, the free spectral range of the spectrum **502** may be determined by reading out or determining the current change $\Delta I(FSR)$ from the spectrum **502**. The term "free spectral range (FSR)" as used herein may refer to the spacing in optical frequency or wavelength between two successive reflected or transmitted optical intensity maxima or minima. In other words, the periodic peaks have a period as determined from $\Delta I(FSR)$.

The wavelength change due to the electrical power supply induced thermo-optical effect may be approximately expressed as:

$$\lambda = AW + C = ARI^2 + C = \frac{AV^2}{R} + C \qquad \text{(Equation 1)}$$

where A is thermal efficient with a unit of nm/W, W is power, R is resistance, for example, of a thermal heater, I is current applied to the tracing resonator and C is a constant value. Power, W, may be expressed as VI or RI^2 or V^2/R, where V is voltage and has the relationship V=RI.

Based on equation 1, the relationship between the resonance wavelength shift, $\Delta\lambda$, and the current change, ΔI, may be given by the equation:

$$\Delta\lambda = 2ARI\Delta I = \frac{2AV\Delta V}{R}. \qquad \text{(Equation 2)}$$

In a microring resonator, the relationship between the resonance shift, $\Delta\lambda$, and the effective refractive index change, Δn_{eff}, may be given by the equation:

$$\Delta\lambda = \frac{\lambda_0}{n_g}\Delta n_{eff} \qquad \text{(Equation 3)}$$

where n_g is the group index of the sensing resonator, λ_0 is the center wavelength of the sensing resonator and n_{eff} is the effective refractive index of the sensing resonator.

Therefore, based on equations 2 and 3, the relationship between the effective refractive index change, Δn_{eff}, and the current change, ΔI, may be given by the equation:

$$\Delta n_{eff} = 2ARI\Delta I\frac{n_g}{\lambda_0}. \qquad \text{(Equation 4)}$$

In various embodiments, the use of the voltage/current scanning method enables the adoption or use of broadband light sources to provide an input light, which eliminates the use of high-resolution wavelength-scanning lasers. Therefore, the detection limit of the optical sensing system of various embodiments depends on the voltage/current sensitivity, where it is much easier to achieve a high resolution current source, compared to the challenge in obtaining a high resolution wavelength-tunable laser, which is a barrier towards achieving small or low detection limit.

The detection limit, DL (RIU), may be defined by the equation:

$$DL = \Delta\lambda/S \qquad \text{(Equation 5)}$$

where S is the sensitivity.

Using a channel waveguide as an example and not limitations, the sensing sensitivity S may be calculated numerically for the channel waveguide. FIG. **6** shows results of numerical simulations for calculating the sensing sensitivity for a channel waveguide structure on silicon-on-insulator (SOI).

FIG. **6**A shows a silicon (Si) channel waveguide **600** having a thickness of about 220 nm and a width of about 450 nm, on a SOI **602**, with the simulated mode field pattern for a transverse magnetic (TM) mode and the corresponding intensity profile **610** of the TM mode. The SOI includes a silicon oxide (SiO) layer having a refractive index of about 1.45. The Si channel waveguide **600**, having a refractive index of about 3.45, is surrounded by a cladding **604** having a refractive index of about 1.33. The mode field extends outside of the channel waveguide **600** and interacts or couples with the cladding layer **604**, thereby enabling sensing of a change in the refractive index of the cladding **604**.

FIGS. **6**B and **6**C show plots **620**, **630**, illustrating the calculated effective refractive index change, based on the TM mode, as functions of the refractive index change, δn, of the upper cladding layer **604** and the wavelength, λ, respectively. The fitting parameters are shown in the plots **620**, **630**, where the calculated data of the plot **620** may be fitted with a linear fit having the relationship (y=0.53541x+1.7518), while the calculated data of the plot **630** may be fitted with a quadratic fit having the relationship ($y=1.5008x^2-6.038x+7.5068$).

Therefore, from the results of plots **620**, **630** of FIGS. **6**B and **6**C, the sensing sensitivity may be calculated based on the equation:

$$S = \frac{\partial \lambda}{\partial n_{clad}} = \frac{\lambda_0}{n_g}\frac{\partial n_{eff}}{\partial n_{clad}} = \frac{\lambda_0}{n_{eff} - \lambda_0\left(\frac{\partial n_{eff}}{\partial \lambda}\right)}\frac{\partial n_{eff}}{\partial n_{clad}}, \quad \text{(Equation 6)}$$

resulting in a sensitivity of approximately 212.73 nm/RIU, where λ_0=1550 nm, n_g~3.9, $\partial n_{eff}/\partial n_{clad}$~0.53541 and n_{eff}~7.5068.

Based on equation 2 and J. Song, et al., *Opt. Express* 16, pp. 15304-15311 (2008), the entire disclosure of which is incorporated herein by reference, the resonance wavelength change, $\Delta\lambda$, as a function of the current change, ΔI, may be calculated or approximated using the equation:

$$\Delta\lambda(\text{nm}) = 80\Delta I(\text{Ampere}) \quad \text{(Equation 7)}$$

with RI approximately 0.5 V assuming R=50Ω and A approximately 0.08 nm/mW.

Therefore, the detection limit, DL (RIU), may be calculated, based on equations 5, 6 and 7, to be approximately 5.6×10^{-6} RIU, assuming 15 μA current sensitivities (i.e. ΔI=15 μA; $\Delta\lambda(\text{nm})=1.2\times10^{-3}$). This is comparable to the wavelength-scanning method which may have a demonstrated best detection limit of approximately 10^{-7}, but with a significantly lower cost. Furthermore, assuming 100 pA current sensitivities (i.e. ΔI=100 pA; $\Delta\lambda$ (nm)=8.0×10^{-9}), the detection limit is approximately 3.8×10^{-11} RIU. In various embodiments, the detection limit may be between about 10^{-5} RIU and about 10^{-11} RIU, depending on the power supply (or current/voltage supply).

FIG. **7**A shows a plot **700** of normalized intensity as a function of wavelength shift for different radii of a microring resonator, according to various embodiments. The plot **700** may be obtained by numerical analysis, for a constant coupling coefficient, κ, of 0.3, n_{eff} of 1.8 for a TM mode and a propagation loss of 3 dB/cm. The coupling coefficient relates to the waveguide-microring resonator coupling.

The plot **700** shows the results for a microring resonator with different radii, R=25 μm **702**, R=50 μm **704**, R=100 μm **706**, R=150 μm **708**, R=200 μm **710** and R=250 μm **712**. The arrow, as represented by **714**, shows the direction of increasing radius of the microring resonator. The plot **700** also shows that as the radius of the microring resonator increases, the quality factor, Q, also increases, and as the quality factor, Q, increases, the difference in the output intensity for the microring resonator with different radii increases.

FIG. **7**B shows a plot **720** of quality factor as a function of microring radius for different coupling coefficients, according to various embodiments. The plot **720** may be obtained by numerical analysis, for n_{eff} of 1.8 for a TM mode and a propagation loss of 3 dB/cm. The plot **720** shows the results for a microring resonator with different coupling coefficients, κ=0.1 **722**, κ=0.2 **724**, κ=0.3 **726**, κ=0.4 **728**, κ=0.5 **730**, κ=0.6 **732**, κ=0.7 **734** and κ=0.8 **736**. The arrow, as represented by **738** shows the direction of increasing coupling coefficient, κ, for the microring resonator.

FIG. **7**C shows a plot **750** of normalized intensity as a function of microring radius for different coupling coefficients, according to various embodiments. The plot **750** may be obtained by numerical analysis, for n_{eff} of 1.8 for a TM mode and a propagation loss of 3 dB/cm. The plot **750** shows the results for microring resonators with different coupling coefficients, κ=0.1 **752**, κ=0.2 **754**, κ=0.3 **756**, κ=0.4 **758**, κ=0.5 **760**, κ=0.6 **762**, κ=0.7 **764** and κ=0.8 **766**. The arrow, as represented by **768** shows the direction of increasing coupling coefficient, κ, for the microring resonator.

The results of FIGS. **7**A to **7**C show that as the radius, R, of a microring resonator increases, the quality factor, Q, increases while the output intensity decreases. In addition, as the coupling coefficient, κ, increases, the quality factor, Q, decreases while the output intensity increases. Therefore, there is a trade-off in the design in terms of the radius and the coupling coefficient of a ring or microring resonator in order to achieve a balance between the quality factor, Q, and the output intensity.

In various embodiments, the sensing sensitivity may be enhanced by enhancing the microring resonator quality factor, for example by balanced microring radius and waveguide-microring coupling. The insertion loss may also be minimised for power detection via enhancement in the design and fabrication process. In addition, on-chip detector or photodetector and/or on-chip light source may be integrated with the optical sensing system of various embodiments. Feedback systems may also be added.

While the invention has been particularly shown and described with reference to specific embodiments, it should be understood by those skilled in the art that various changes in form and detail may be made therein without departing from the spirit and scope of the invention as defined by the appended claims. The elements of the various embodiments may be incorporated into each of the other species to obtain the benefits of those elements in combination with such other species, and the various beneficial features may be employed in embodiments alone or in combination with each other. The scope of the invention is thus indicated by the appended claims and all changes which come within the meaning and range of equivalency of the claims are therefore intended to be embraced.

What is claimed is:

1. An optical sensing system, comprising:

a resonator arrangement comprising:

a first resonator, wherein an effective refractive index of the first resonator is changeable in response to a change in a refractive index of a cladding of the first resonator; and

a second resonator to which a current or voltage being adjustable in response to a change in the effective refractive index of the first resonator is applied;

wherein the optical sensing system is configured to determine the change in the effective refractive index of the first resonator based on a change in the current or voltage applied to the second resonator.

2. The optical sensing system of claim **1**, wherein the second resonator comprises a thermal heater, and wherein the current or voltage being adjustable in response to a change in the effective refractive index of the first resonator is applied to the thermal heater.

3. The optical sensing system of claim **1**, further comprising:

an input optical waveguide configured to guide received light;

wherein the resonator arrangement is coupled to the input optical waveguide to receive the light from the input optical waveguide.

4. The optical sensing system of claim **1**, further comprising:

a coupling optical waveguide coupled between the first resonator and the second resonator, the coupling optical waveguide being configured to guide light received from the first resonator to the second resonator or from the second resonator to the first resonator.

5. The optical sensing system of claim **4**, further comprising:

an input optical waveguide configured to guide received light, wherein the resonator arrangement is coupled to the input optical waveguide to receive the light from the input optical waveguide; and

an output optical waveguide coupled to the resonator arrangement, the output optical waveguide being configured to output light received from the resonator arrangement,

wherein the first resonator is coupled to the input optical waveguide and the coupling optical waveguide, and the second resonator is coupled to the output optical waveguide and the coupling optical waveguide.

6. The optical sensing system of claim **5**,

wherein the first resonator has an input port coupled to the input optical waveguide and an output port coupled to the coupling optical waveguide, wherein the first resonator is configured to receive light from the input optical waveguide via the input port, direct the light to the output port, and transmit the light to the coupling optical waveguide via the output port.

7. The optical sensing system of claim **5**,

wherein the second resonator has an input port coupled to the coupling optical waveguide and an output port coupled to the output optical waveguide, wherein the second resonator is configured to receive light from the coupling optical waveguide via the input port, direct light from the input port to the output port, and transmit the light to the output optical waveguide via the output port.

8. The optical sensing system of claim **4**, further comprising:

an input optical waveguide configured to guide received light, wherein the resonator arrangement is coupled to the input optical waveguide to receive the light from the input optical waveguide; and

an output optical waveguide coupled to the resonator arrangement, the output optical waveguide being configured to output light received from the resonator arrangement,

wherein the second resonator is coupled to the input optical waveguide and the coupling optical waveguide, and the first resonator is coupled to the output optical waveguide and the coupling optical waveguide.

9. The optical sensing system of claim **8**,

wherein the second resonator has an input port coupled to the input optical waveguide and an output port coupled to the coupling optical waveguide, wherein the second resonator is configured to receive light from the input optical waveguide via the input port, direct the light to the output port, and transmit the light to the coupling optical waveguide via the output port.

10. The optical sensing system of claim **8**,

wherein the first resonator has an input port coupled to the coupling optical waveguide and an output port coupled to the output optical waveguide, wherein the first resonator is configured to receive light from the coupling optical waveguide via the input port, direct light from the input port to the output port, and transmit the light to the output optical waveguide via the output port.

11. The optical sensing system of claim **1**, further comprising:

an output optical waveguide coupled to the resonator arrangement, the output optical waveguide being configured to output light received from the resonator arrangement.

12. The optical sensing system of claim **11**, further comprising:

a detector coupled to the output optical waveguide,

wherein the detector is configured to receive light from the output optical waveguide.

13. The optical sensing system of claim **12**,

wherein the detector is configured to measure an intensity of light received from the output optical waveguide.

14. The optical sensing system of claim **13**,

wherein the intensity of light is maximum when an optical resonant frequency of the first resonator and an optical resonant frequency of the second resonator are aligned.

15. The optical sensing system of claim **14**,

wherein the optical resonant frequency of the first resonator changes in response to the change in the effective refractive index of the first resonator.

16. The optical sensing system of claim **15**,

wherein the optical sensing system is configured to change the current or voltage applied to the second resonator to align the optical resonant frequency of the second resonator with the changed optical resonant frequency of the first resonator such that the intensity of light measured by the detector is maximum.

17. The optical sensing system of claim **1**,

wherein the first resonator and the second resonator are identical.

18. The optical sensing system of claim **17**,

wherein the first resonator and the second resonator each comprises a closed loop.

19. The optical sensing system of claim **18**,

wherein the closed loops are ring-shaped.

20. The optical sensing system of claim **1**, further comprising:

a light source configured to provide light.

21. The optical sensing system of claim **20**,

wherein the light source comprises a broadband light source.

* * * * *